

## IN THE CLAIMS

The following is a complete listing of the claims, and replaces all earlier versions and listings.

1. (Currently Amended) A method of manufacturing an electronic device, comprising the steps of:

moving, relative to each other, a droplet ejecting portion of an ink jet device and a substrate, to which ~~[[a]]~~ droplets are ~~[[is]]~~ to be ejected, ~~relatively~~ in an ~~in-surface~~ direction along a droplet-receiving surface of ~~said the~~ substrate, and detecting a distance between ~~said the~~ ejecting portion and ~~[[a]] the~~ droplet-receiving ~~given~~ surface ~~on-said of~~ the substrate; and

ejecting toward a plurality of portions separated mutually on the substrate at plural times at a predetermined time interval ~~intermittently~~ the droplets of a liquid containing material for forming the electronic device, wherein the predetermined time interval is controlled based on a result of the detecting~~upon the moving under a control of the distance based on a detection result.~~

2. (Cancelled)

3. (Currently Amended) A method of manufacturing an electronic device as claimed in claim 1, wherein the detecting of the distance includes a step of

measuring the distances between ~~said the~~ ejecting portion and ~~predetermined the plurality~~  
of portions separated mutually on the substrate.

4. (Currently Amended) A method of manufacturing an electronic device as claimed in claim, 1 wherein the detecting of the distance includes a step of measuring a distance between ~~said the~~ ejecting portion and one or some of ~~predetermined the plurality of~~ portions separated mutually on the substrate.

5. (Currently Amended) A method of manufacturing an electronic device as claimed in claim 1, wherein the detecting of the distance includes a step of measuring a distance between ~~said the~~ ejecting portion and one or some of ~~predetermined the plurality of~~ portions separated mutually on the substrate, and a step of calculating the distances between ~~said the~~ ejecting portion and others of ~~predetermined the plurality of~~ portions separated mutually on the substrate, based on the result of the measuring.

6. (Cancelled)

7. (Currently Amended) A method of manufacturing an electronic device, comprising the steps of:

moving, relative to each other, a droplet ejecting portion of an ink jet device and a substrate, to which ~~[[a]] droplets are [[is]]~~ to be ejected, ~~relatively~~ in an in-surface

direction along a droplet-receiving surface of ~~said the~~ substrate, ~~and while~~ detecting a distance between ~~said the~~ ejection portion and ~~[[a]] the droplet-receiving given surface on~~ ~~said of the~~ substrate; and

ejecting toward a plurality of portions separated mutually on the substrate at plural times intermittently at a predetermined time interval the droplets of a liquid containing material for forming the electronic device, wherein the predetermined time interval is controlled based on ~~upon the moving, a timing of the ejecting varied according to~~ a result of the detecting.

8.-17. (Cancelled)

18. (Currently Amended) A method of manufacturing an electronic device as claimed in claim 1, wherein ~~said the~~ ink jet device is of a ~~system of giving a type that imparts~~ thermal energy to the liquid to produce a bubble, ~~[[to]] thereby to eject the a~~ droplet.

19. (Currently Amended) A method of manufacturing an electronic device as claimed in claim 1, wherein ~~said the~~ ink jet device is of a ~~system of ejecting type that ejects~~ the droplets by means of a piezo-electric element.

20. (Currently Amended) A method of manufacturing an electron source having a plurality of ~~electron emission elements~~ electron-emitting devices, comprising the steps of:

moving, relative to each other, a droplet ejecting portion of an ink jet device and a substrate, to which ~~[[a]] droplets are [[is]]~~ to be ejected, ~~relatively in an in-surface~~ direction along a droplet-receiving surface of ~~said the~~ substrate; and;

detecting a distance between ~~said the~~ ejecting portion and ~~[[a]] the~~ droplet-receiving ~~given~~ surface ~~on said of the~~ substrate; and

ejecting to a plurality of portions separated mutually on the substrate at plural times ~~intermittently~~ at a predetermined time interval the droplets of a liquid containing material for forming a conductive member of the electron-emitting device, wherein the predetermined time interval is determined based on a result of the detecting upon the moving under controlling the distance based on a detection result.

21. (Cancelled)

22. (Currently Amended) A method of manufacturing an electron source as claimed in claim 20, wherein the detecting of the distance includes a step of measuring the distances between ~~said the~~ ejecting portion and ~~predetermined and the~~ plurality of portions separated mutually on the substrate.

23. (Currently Amended) A method of manufacturing an electron source as claimed in claim 20, wherein the detecting of the distance includes a step of measuring a distance between ~~said the~~ ejecting portion and one or some of ~~predetermined~~ the plurality of portions separated mutually on the substrate.

24. (Currently Amended) A method of manufacturing an electron source as claimed in claim 20, wherein the detecting of the distance includes a step of measuring a distance between ~~said the~~ ejecting portion and one or some of ~~predetermined~~ plurality of portions separated mutually on the substrate, and a step of calculating the distances between ~~said the~~ ejecting portion and others of the ~~predetermined~~ plurality of portions separated mutually on the substrate, based on a result of the measuring.

25. (Cancelled)

26. (Currently Amended) A method of manufacturing an electron source having a plurality of electron-emitting devices, comprising the steps of:  
moving, relative to each other, a droplet ejection portion on an ink jet device and a substrate, to which ~~[[a]]~~ droplets are ~~[[is]]~~ to be ejected, relatively in an in-surface direction along a droplet-receiving surface of ~~said the~~ substrate, and while detecting a distance between ~~said the~~ ejecting portion and ~~[[a]]~~ the droplet-receiving given surface on ~~said of the~~ substrate; and

ejecting to a plurality of portions separated mutually on the substrate at plural times ~~intermittently~~ at a predetermined time interval the droplets of a liquid containing material for forming the ~~electronic~~ electron-emitting device upon the moving, ~~a timing of the ejecting varied according to~~ wherein the predetermined interval is controlled based on a result of the detecting.

27. - 70. (Cancelled)

71. (Currently Amended) A method of manufacturing an electron source as claimed in claim 20, wherein ~~said the~~ ink jet device is of a ~~system of giving a type that imparts~~ thermal energy to the liquid to produce a bubble, [[to]] thereby to eject ~~the a~~ droplet.

72. (Currently Amended) A method of manufacturing an electron source as claimed in claim 20, wherein ~~said the~~ ink jet device is of a ~~system of ejecting type that ejects~~ the droplets by means of a piezo-electric element.

73. (Currently Amended) A method of manufacturing an image forming apparatus having an electron source and an image forming member onto which electrons are irradiated from ~~said the~~ electron source, ~~characterized in that said~~ wherein the electron source is one that has been manufactured by a method as claimed in claim 20.

74. - 94. (Cancelled)

95. (Currently Amended) A method of manufacturing an electronic device as claimed in claim 7, wherein ~~said~~ the ink jet device ejects the liquid droplet by applying thermal energy to the liquid to generate a bubble in the liquid.

96. (Currently Amended) A method of manufacturing an electronic device as claimed in claim 7, wherein ~~said~~ the ink jet device ejects the liquid droplet by means of a piezo-electric element.

97. (Currently Amended) A method of manufacturing an electron source as claimed in claim 26, wherein ~~said~~ the ink jet device ejects the liquid droplets by applying thermal energy to the liquid to generate a bubble in the liquid.

98. (Currently Amended) A method of manufacturing an electron source as claimed in claim 26, wherein ~~said~~ the ink jet device ejects the liquid droplets by means of a piezo-electric element.

99. (New) A method of manufacturing an electronic device as claimed in claim 7, wherein the detecting of the distance includes a step of measuring the distance

between the ejecting portion and the plurality of portions separated mutually on the substrate.

100. (New) A method of manufacturing an electronic device as claimed in claim 7, wherein the detecting of the distance includes a step of measuring a distance between the ejecting portion and one or some of the plurality of portions separated mutually on the substrate.

101. (New) A method of manufacturing an electronic device as claimed in claim 7, wherein the detecting of the distance includes a step of measuring a distance between the ejecting portion and one or some of the plurality of portions separated mutually on the substrate, and a step of calculating the distances between the ejecting portion and the others of the plurality of portions separated mutually on the substrate, based on the result of the measuring.

102. (New) A method of manufacturing an electron source as claimed in claim 26, wherein the detecting of the distance includes a step of measuring the distances between the ejecting portion and the plurality of portions separated mutually on the substrate.



103. (New) A method of manufacturing an electron source as claimed in claim 26, wherein the detecting of the distance includes a step of measuring a distance between the ejecting portion and one or some of the plurality of portions separated mutually on the substrate.

104. (New) A method of manufacturing an electron source as claimed in claim 26, wherein the detecting of the distance includes a step of measuring a distance between the ejecting portion and one or some of the plurality of portions separated mutually on the substrate, and a step of calculating the distances between the ejecting portion and the others of the plurality of portions separated mutually on the substrate, based on the result of the measuring.

105. (New) A method of manufacturing an image forming apparatus having an electron source and an image forming member onto which electrons are irradiated from the electron source, wherein the electron source is manufactured by a method as claimed in claim 26.